

# XRnanotech

Nanostructures and Optics  
with Swiss Precision

Dr. sc. ETHZ Gérard Perren

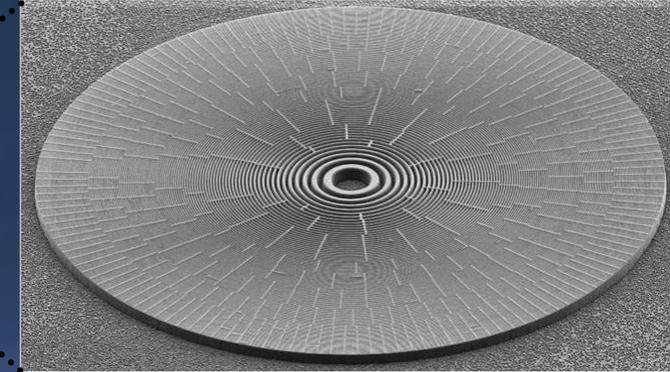
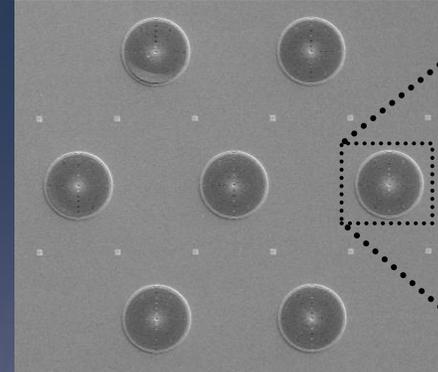
Manager, Innovation & Business Development | XRnanotech

[gerard.perren@xrnanotech.ch](mailto:gerard.perren@xrnanotech.ch)

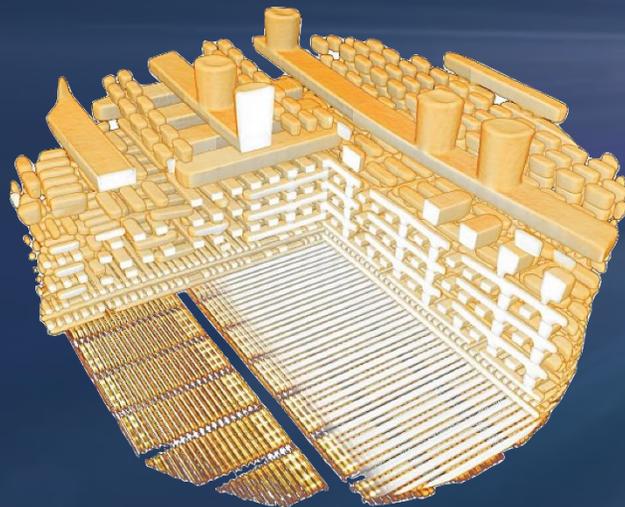
12.06.2025

## Award Winning Manufacturing with Swiss Product Excellence

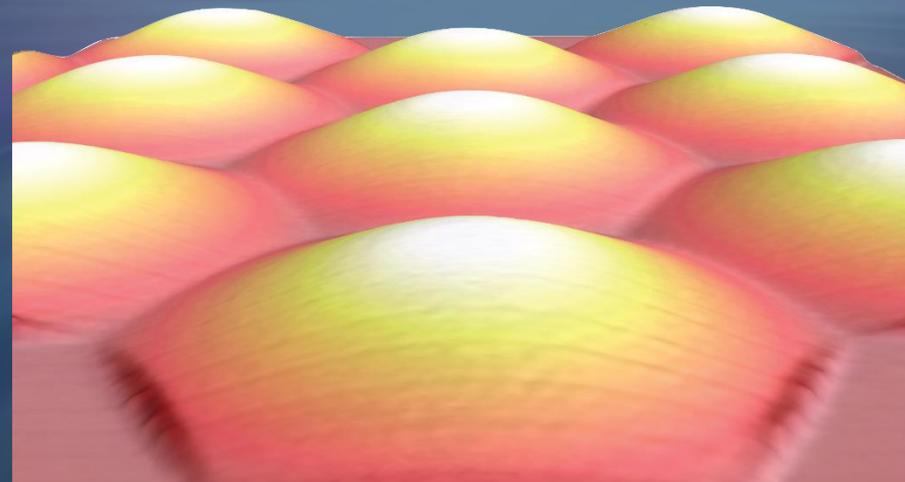
SWISS EXCELLENCE  STIFTUNG



EUV and X-ray Optical  
Components & Systems



Nano and micro-  
structured Metamaterials



Neutron Optical  
Components



Founded February 2020



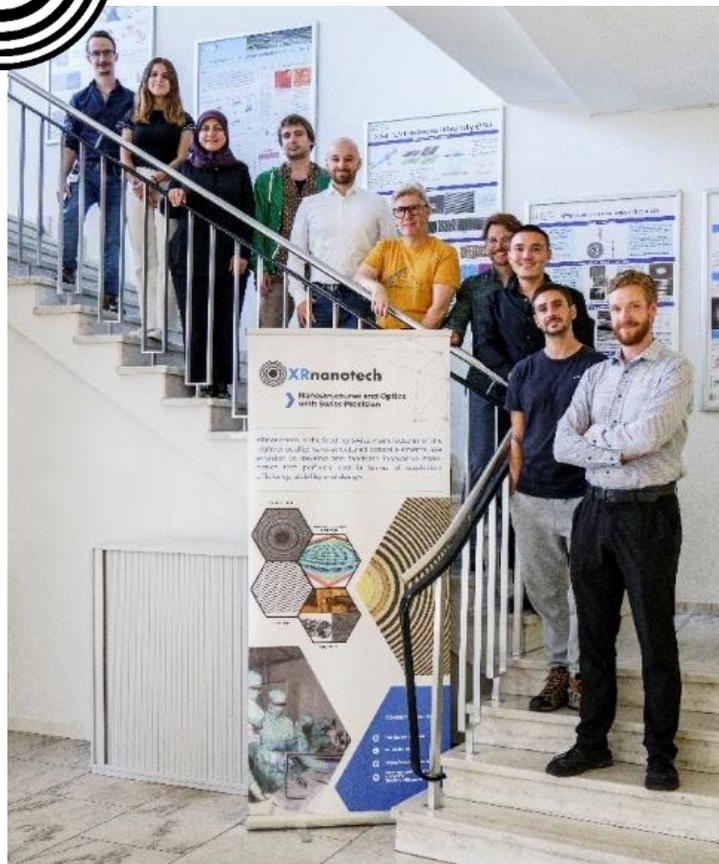
Team of 27 people



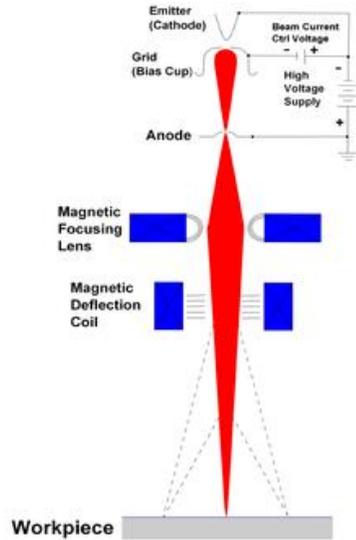
Innovative products covering nanostructures and optics



Flexible Fab for rapid micro and nano prototyping

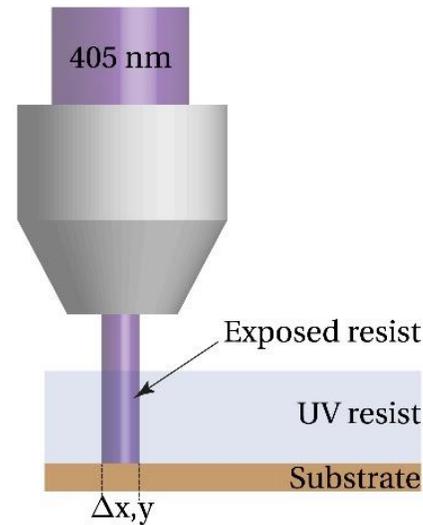


E-beam lithography



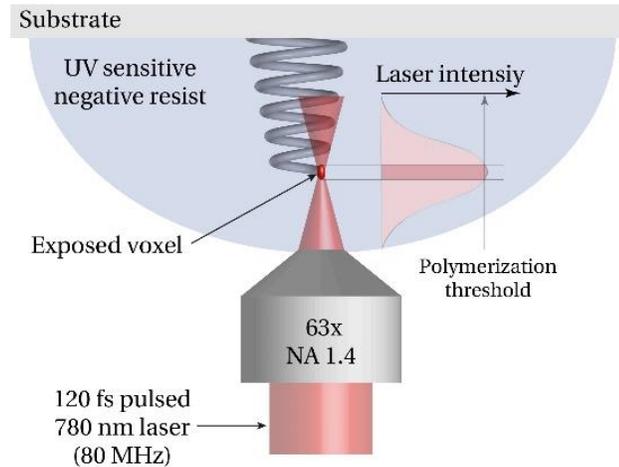
- Feature Size > 10 nm
- Good stitching
- Writing times
- Charging effects
- Up to 4  $\mu\text{m}$  height

Laser lithography



- Feature Size > 500 nm
- Good stitching
- Fast writing times
- No substrate effect
- Up to 100  $\mu\text{m}$  height

3D Printing  
(2 Photon polymerization)



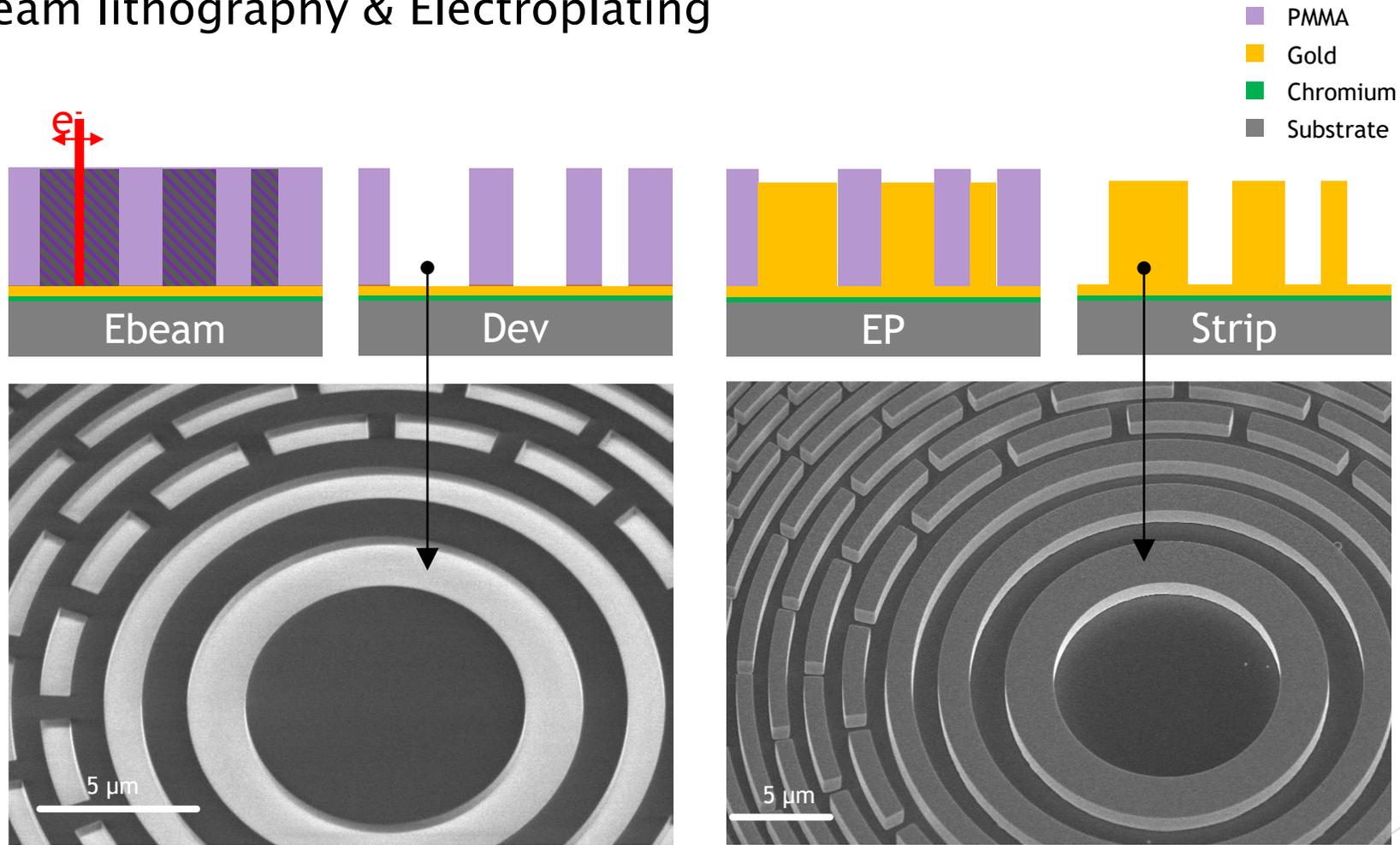
- Feature Size > 150 nm
- Good stitching
- Slow writing times
- No substrate effect
- True 3D vs. 2.5D

LIGA  
(X-ray lithography & Electroplating)

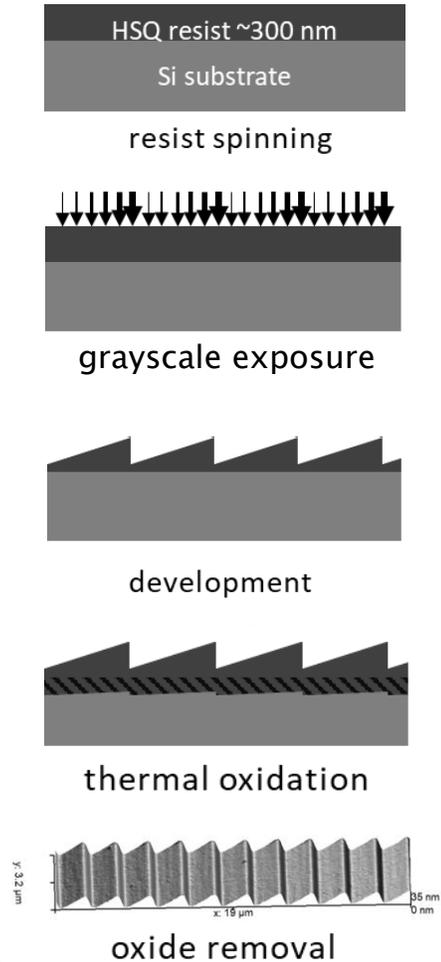


- Feature Size > 10  $\mu\text{m}$
- Good stitching
- Slow writing times
- No substrate effect
- Up to 1000  $\mu\text{m}$  height

### E-beam lithography & Electroplating



### Grayscale EBL and through-mask oxidation



#### Spin coating

- HSQ resist, thickness ~ 300 nm

#### Grayscale exposure

- Exposed area is converted to SiO<sub>x</sub>

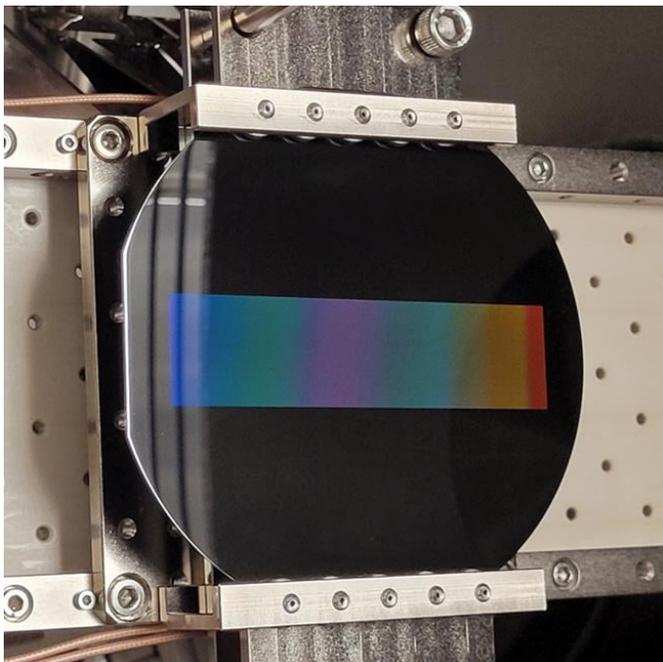
#### Development

- NaOH-based developer

#### Thermal oxidation

- Dry oxidation, different SiO<sub>x</sub> thickness → different oxidation speed

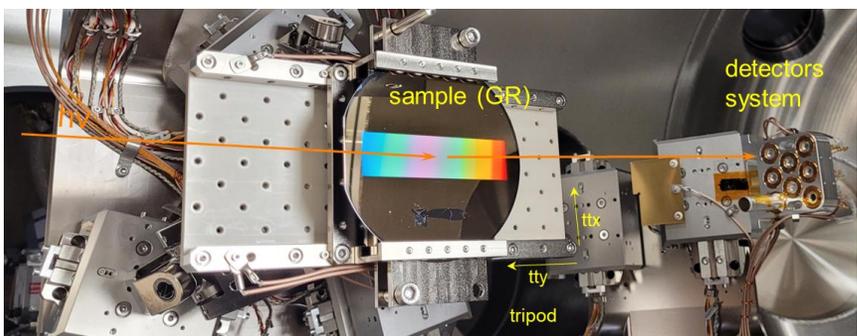




Result: Smooth surface due to height feature reduction (10x)



oxide removal



*Class 10/ISO 4 1000 m2 cleanroom at PSI*

Lithography techniques: EBL, Laser, LIGA

Electroplating & Deposition\*:

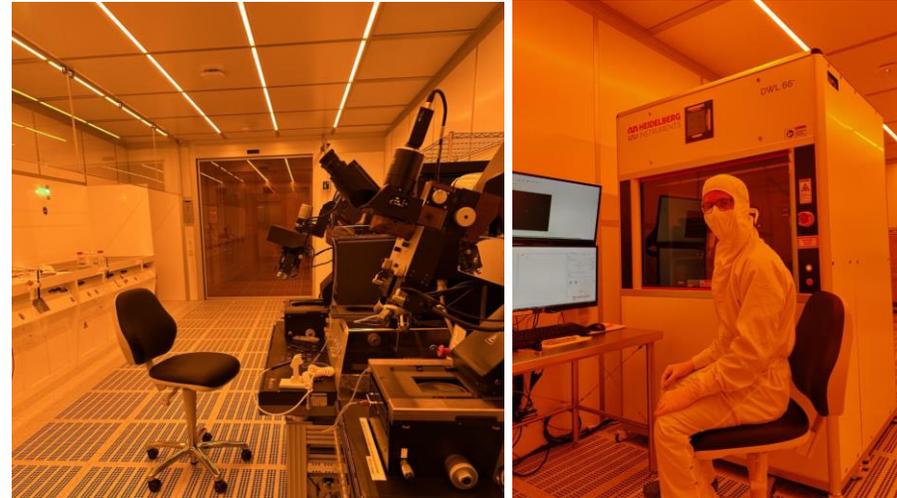
- Au & Ni
- Cr, Ru, Mo, Al

Etching/Wet chemistry\*:

- Si, SiO<sub>2</sub>, Diamond

Collaborations:

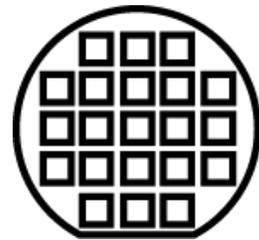
- Nanoimprint lithography & Atomic Layer Deposition (ALD) of metal oxides



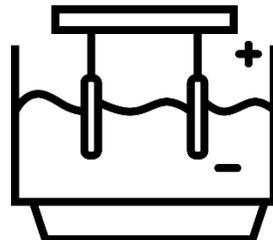
1. **Initial Contact:** Web-based inquiry and/or direct contacting
2. **Consulting phase:** Feasibility, Materials, Design, Lead times, and Project type (Order, R&D, Supplier agreement, etc.)
3. **Implementation phase:** Project type dependent
4. **Delivery and Services:** Metrology/Inspection



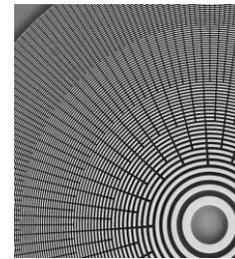
CAD design



Laboratory Processing and Writing



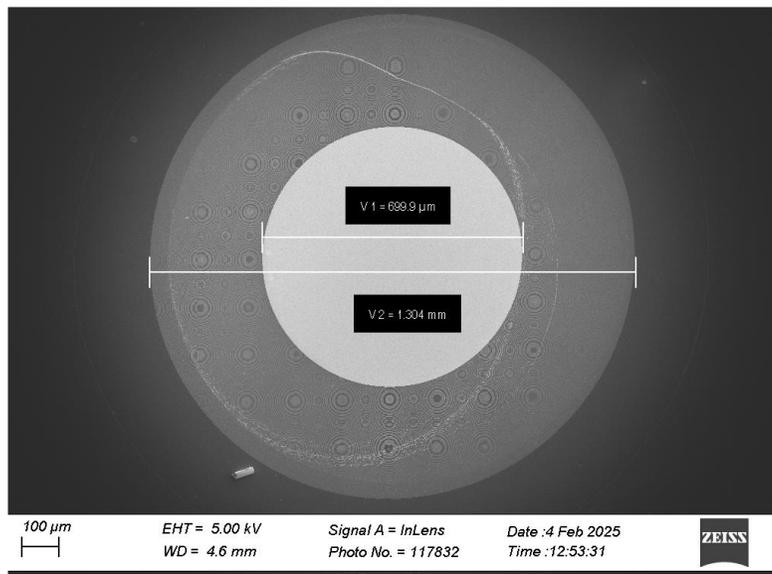
Electroplating and Post-Processing



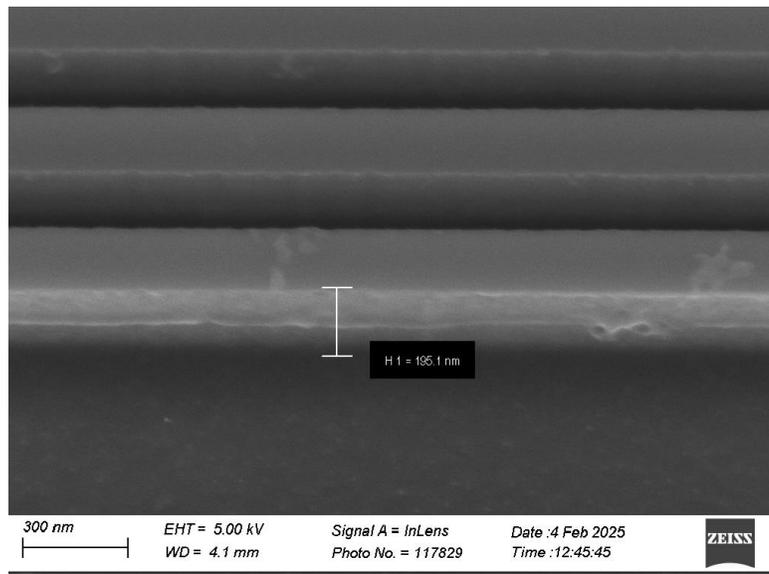
SEM Inspection



SEM image, top view

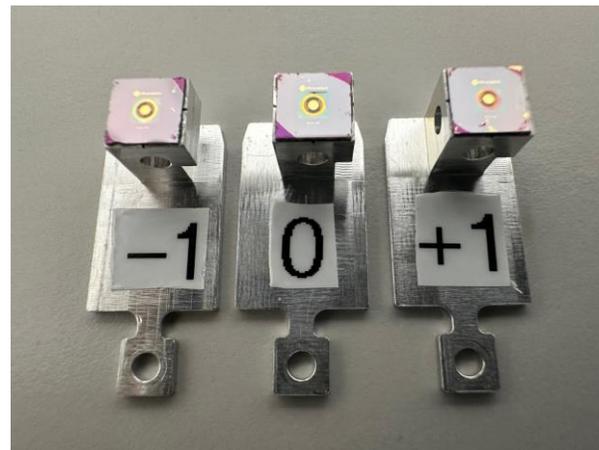


SEM image, side view



### Specifications

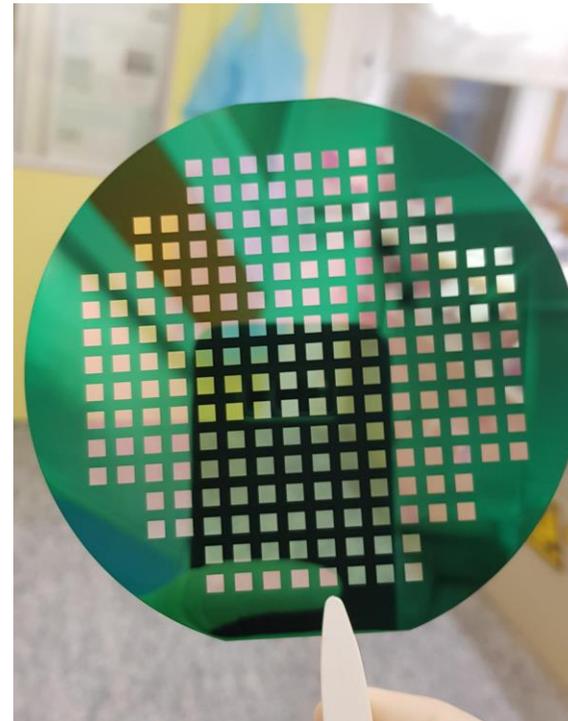
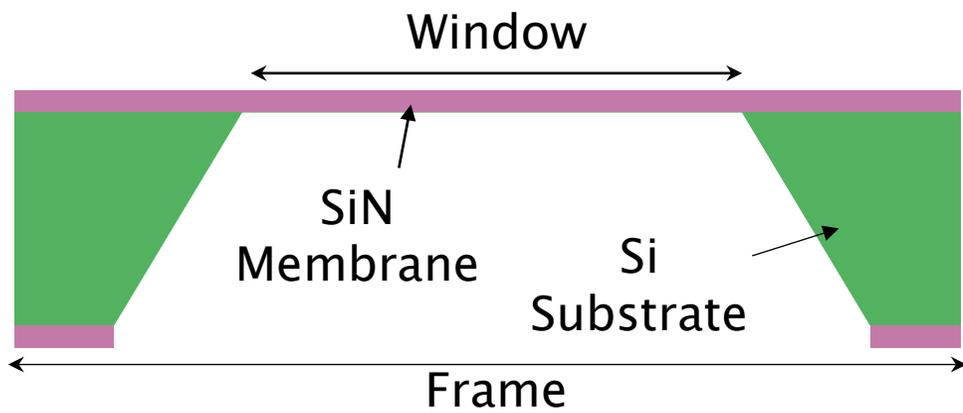
- Contrast material: Si
- Thickness: 400 nm
- $\varnothing$ : 1300 nm
- drN: 200 nm



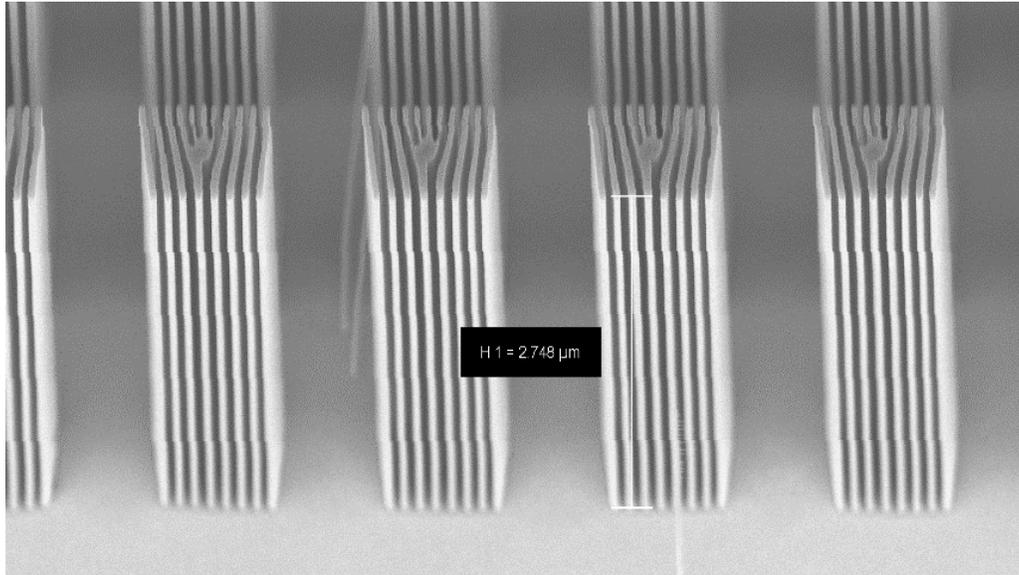
*A brief overview on substrates and membranes, aka chips*

Chips consist of a solid Si frame featuring membrane windows of

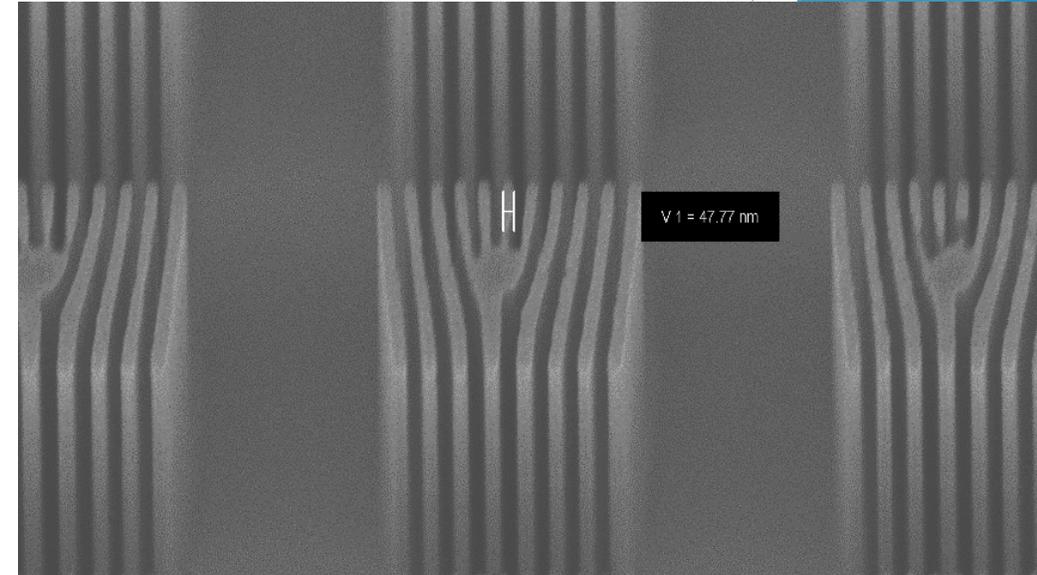
- $\text{Si}_3\text{N}_4$  /  $\text{SiC}$  / Si with thicknesses ranging from
- 50 nm to 1  $\mu\text{m}$ , and lateral sizes of
- 9 x 9 mm, 6 x 6 mm, 3 x 3 mm & custom-made



SEM image, side view



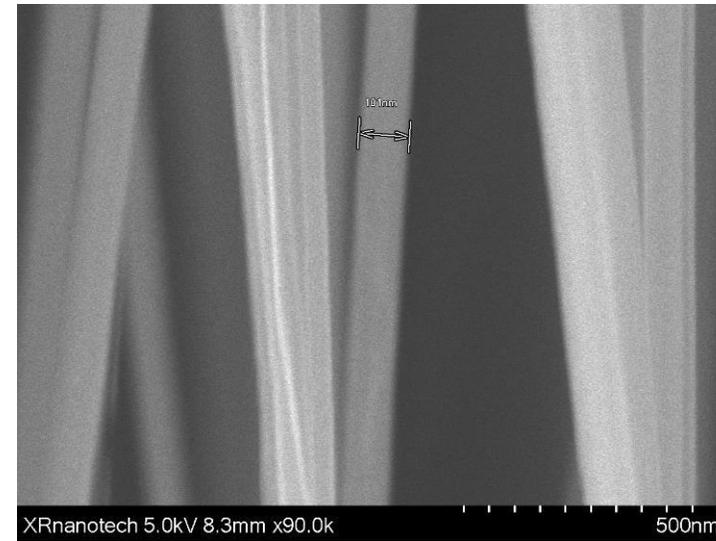
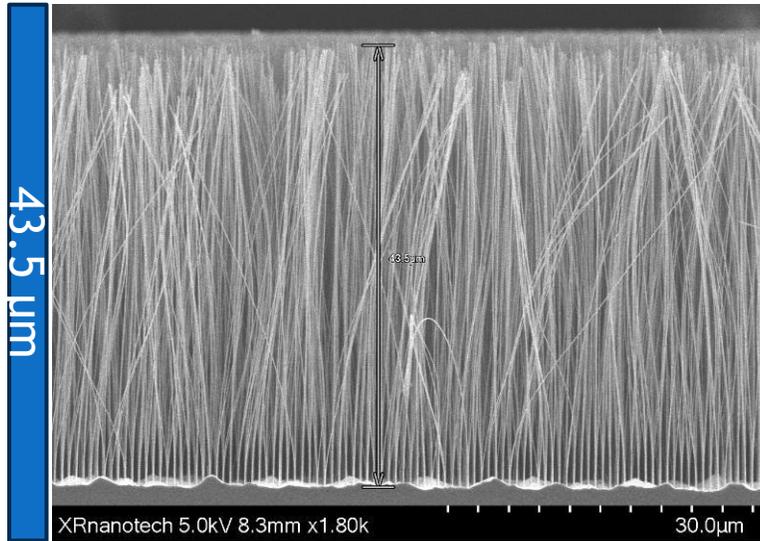
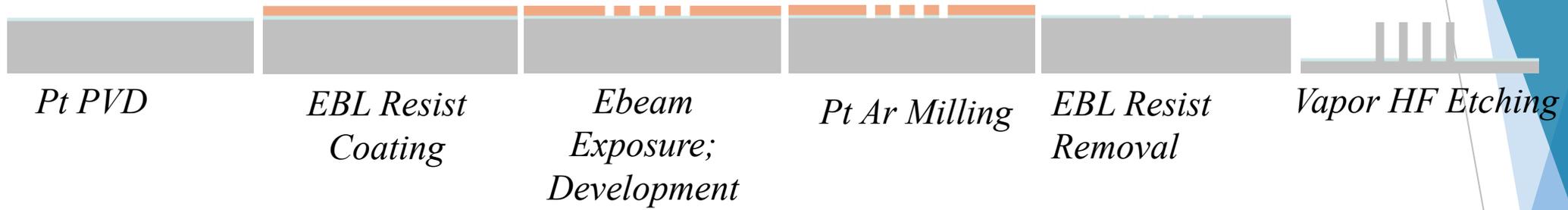
SEM image, side view



## Specifications

- Contrast material: Si
- Height:  $> 5 \mu\text{m}$
- Area:  $5 \times 5 \text{ mm}$
- Pitch:  $100 \text{ nm}$

*A brief overview of the process for achieving high-aspect ratios in Si,  
MACE: Metal Assisted Chemical Etching*





# XRnanotech

*Nanostructures & Optics with Swiss precision!*



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[www.xrnanotech.com](http://www.xrnanotech.com)



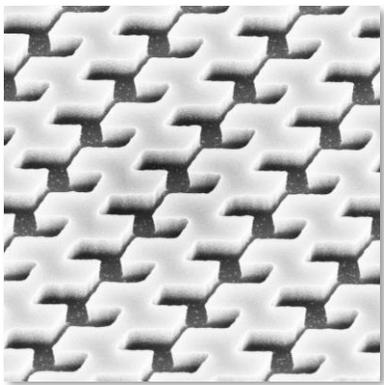
[info@xrnanotech.ch](mailto:info@xrnanotech.ch)



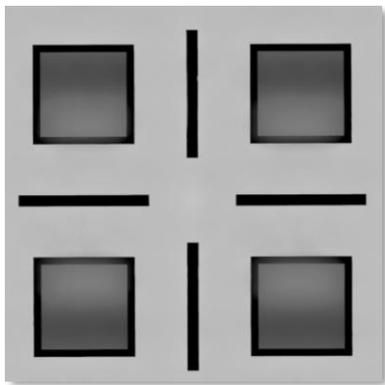
# Thank you!

Any question?





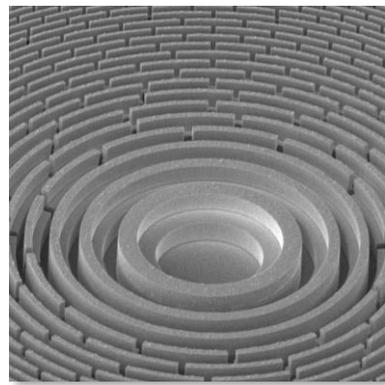
Custom optics



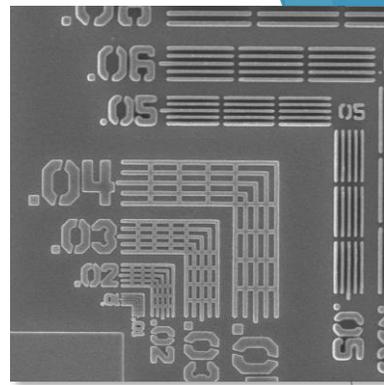
Thin membranes



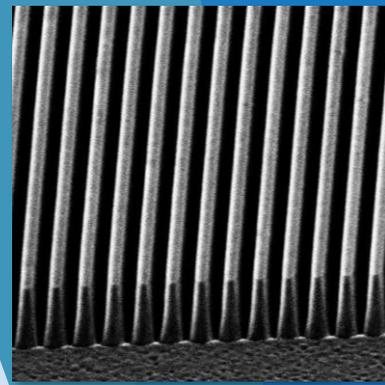
Siemens Stars



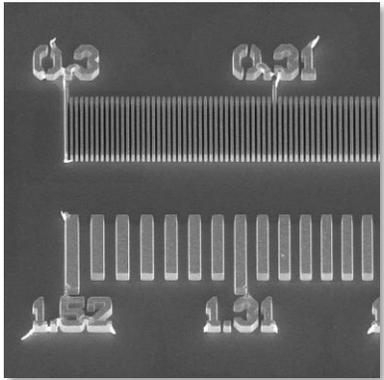
Blazed zone plates



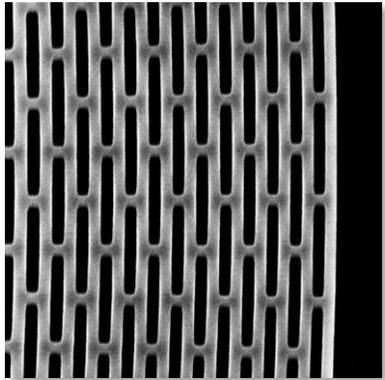
Hybrid targets



Diamond gratings



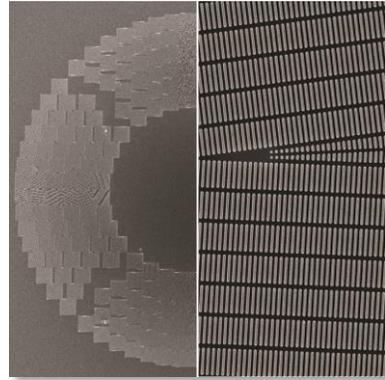
VLS gratings



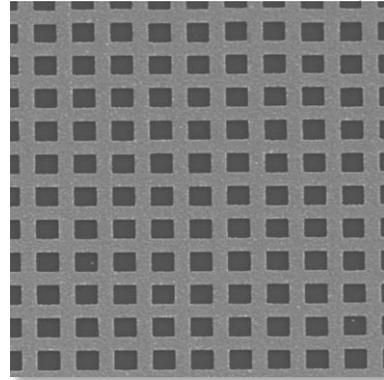
EUV zone plates



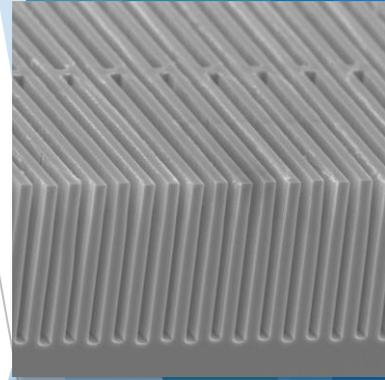
3D Siemens Stars



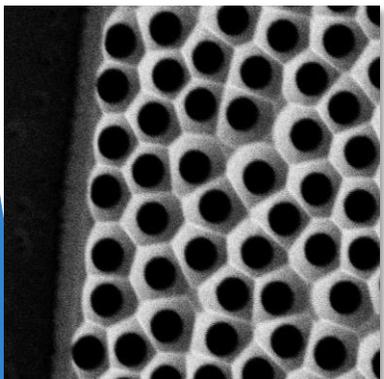
Condenser lenses



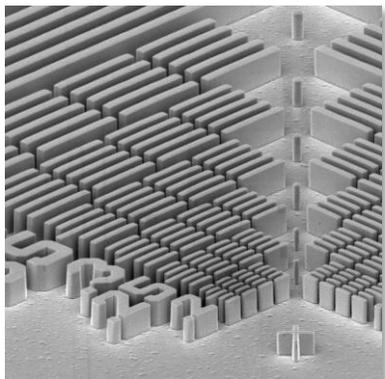
Wavefront sensors



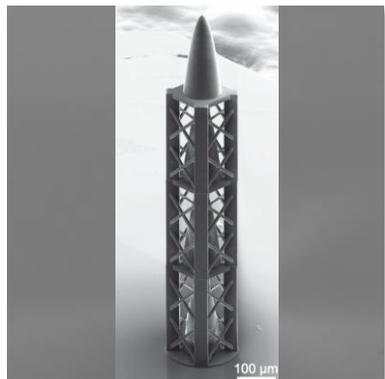
Silicon grating



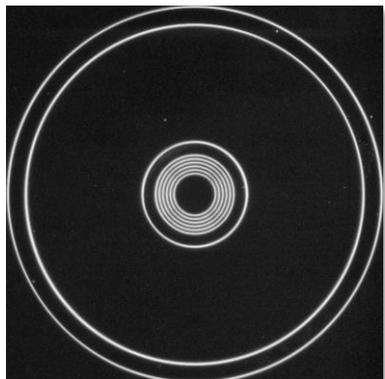
Diamond diffusers



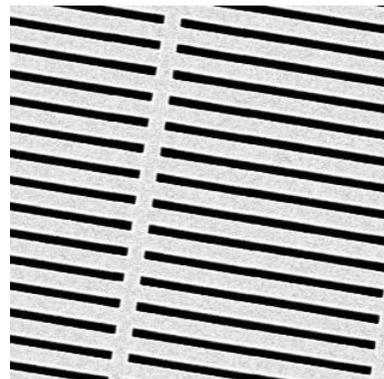
MicroCT targets



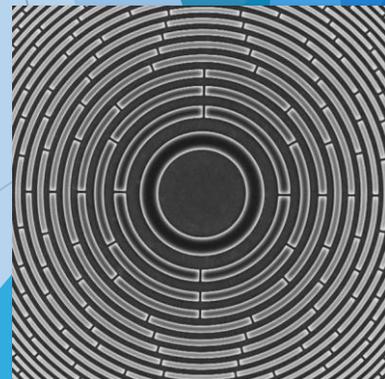
Achromatic lenses



Phase rings



Metal gratings



Fresnel zone plates